



Japan Gases & Facilities Committee Meeting Summary and Minutes

SEMI Japan Standards Summer 2013 Meetings Friday, June 28, 2013, 15:00-17:00 SEMI Japan, Tokyo, Japan

Next Committee Meeting

SEMI Japan Standards Fall 2013 Meetings Friday, September 27, 2013, 15:00-17:00 SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan) **SEMI Staff:** Naoko Tejima (SEMI Japan)

Company	Last	First	Company	Last	First
Hitachi High Technologies	Enami	Hiromichi	Tokyo Electron Yamanashi	Moriya	Shuji
Swagelok	Ishida	Noritsugu	Tokyo Electron Tohoku	Okabe	Tsuneyuki
Flow Techno Service	Ishihara	Seiji	HORIBA STEC	Shimizu	Tetsuo
HORIBA STEC	Isobe	Yasuhiro	Hitachi Metals	Sugimoto	Masato
Brooks Instrument	Kashiwazaki	Hokuto	MKS Japan	Suzuki	Isao
Fujikin	Machii	Yoshifumi	Fujikin	Tsujitani	Hideo
ACE	Mihira	Hiroshi	SEMI Japan	Naoko	Tejima

* alphabetical order by last name

Table 2 Leadership Changes

Group	Previous Leader	New Leader
Standardization of Live Gas Flow Rate Study Group		Shuji Moriya (Tokyo Electron Yamanashi)

Table 3 Ballot Results

None

Table 4 Authorized Ballots

None

Table 5 Authorized Activities

#	Type	SC/TF/WG	Details
			A study group was newly set up to explore the possibility of the Standardization of live Gas Flow.





Table 6 New Action Items

Item #	Assigned to	Details
G+F130628-01		 To prepare for a small workshop / an enlarged committee meeting regarding the measurement of the small particles in the gas components and systems at SEMICON Japan 2013 (December 5). Invite some speakers from a device manufacturer, a measurement equipment manufacturer or a University.

1 Welcome, Reminders and Introductions

Isao Suzuki, committee co-chair, called the meeting to order at 15:00. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Naoko Tejima.

3 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on March 22, 2013.

Motion:	To approve the minutes of the previous meeting as written.		
By / 2 nd :	Hiroshi Mihira (ACE) / Seiji Ishihara, (Flow Techno Service)		
Discussion:	None		
Vote:	10 in favor and 0 opposed. Motion passed.		
Attachment:	01_JA_G+F_Previous_Mtg_Minutes_130628		

4 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2013 Calendar of Events, Global Standards Meeting Schedule, NA Standards Meetings in conjunction with SEMICON West, 2013 Critical Dates for SEMI Standards Ballots, SEMI Standards Publication, SEMICON Japan 2013 Information and Contact Information.

Attachment: 02_SEMI_Staff_Report_130628

5 Liaison Reports

5.1 North America Facilities and Gases Committee

Naoko Tejima briefly reported for the North America Facilities and Gases Committee. This report included Leadership, Current Committee Organization, Meeting Information, New TFOF and SNARFs, Ballot Results Summary, Upcoming Ballots for Cycle 3 & 4, 2013 and Subcommittee and Task Force Activities Highlights.

There was a question, "what is the scope of a new TF and the document #5595?" The TFOF and the SNARF are as below.

- TIFOF: Surface Mount Sandwich Component Dimensions TF
 http://downloads.semi.org/web/wstdsbal.nsf/0e0afa4c4969bea688256efd0062a27c/6477d2b9a98fdad088257b5c0067f1dd!OpenDocument
- SNARF: Doc.#5595, New Standard: Guide for the Development of Dimensional Standards for "Sandwich" Surface Mount Components.

http://downloads.semi.org/web/wstdsbal.nsf/0e0afa4c4969bea688256efd0062a27c/72ff8a145e42c1a988257b5c0068372e!OpenDocument to the semicondex of the semicon

Attachment: 03_NA_Facilities_and_Gases_Comm_Report_130628





5.2 Europe Gases and Liquid Chemicals Committee

No report was provided.

5.3 Korea Facilities Committee

No report was provided.

6 Task Force Reports

6.1 Fl Revision Task Force

Yoshifumi Machii reported for the F1 Revision Task Force that there were not particular activities.

6.2 Gas Panel and Metal Seal Test Methods Task Force

Yoshifumi Machii reported for the Gas Panel and Metal Seal Test Methods Task Force that there were not particular activities.

6.3 5-year-review Task Force

Yoshifumi Machii reported for the 5-year-review Task Force that there were not particular activities.

Naoko Tejima reported the below document is subject to the five-year review and requested the task force to work for it.

• SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System.

7 Old Business

7.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

Item #	Assigned to	Details
G+F121205-03	Noritsugu Ishida	To ask ASME to contact SEMI staff, if they need to revise the existing SEMI standards documents or to develop the new SEMI standards documents Close ASME turned down this request
G+F130322-01	SEMI	To check the question as below; When the topics about the export restriction of US technologies by US government come up for discussion at the standards meeting, how are they handled? Is it defined in SEMI Standards Regulations? Close
G+F130322-02	SEMI	To check whether there are some documents for 5-year-review procedure Close
G+F130322-03	Isao Suzuki	To ask Hiromichi Enami to make a summary of the proposal regarding the small particles in the gas components and systems so that it will be distributed with the next committee meeting agenda Close
G+F130322-04	SEMI	To check whether there are the development of the documents (new, revised or reapproval) regarding the small particles in the gas components and systems Close





8 New Business

8.1 Discussion on the measurement of the small particles in the gas components and systems

Hiromichi Enami presented current issues of the measurement method of small particles in the gas components and systems. According to his presentation, Standards of the measurement of small particles was not newly developed since it was published before 2000. At that time, since the design rule was 90nm line scale, it was satisfied if the small particle with the size of 0.1 micron or more could be found. However, currently, the line scale has been narrow until 16 nm and it would become narrow more and more. The existing Standards are out of date any more, and the new standards for this issue seem to need to be developed.

For the meantime, a discussion to exchange opinions and to do a brainstorming will be held within the committee several times, and when the issues which should be standardized will be found, then TF will be established and will start to develop it.

Action Item: Hiromichi Enami and Isao Suzuki to prepare for a small workshop / an enlarged committee meeting at SEMICON Japan 2013 (December 5)

• Invite some speakers from a device manufacturer, a measurement equipment manufacturer or a University.

8.2 Proposal of Standardization of Live Gas Flow Rate

Shuji Moriya proposed to discuss the Standardization of live Gas Flow Rate and he explained its background as follows;

There are various flow rate controllers made by many manufacturers, and its flow rate is different between among the manufacturers and the models. These matters have existed heretofore, however, currently, they have risen up to the surface. Sometimes, in the sensitive process, when the device manufacturer changed the flow rate equipment, they can not trace the process conditions. Also, the case which is used the new liquid materials is increasing, however, when it is used, there are no Standards how to decide the flow rate.

Responding to the above, the followings were proposed.

- To form the study group
- To sort out the issues and action assignment
- To determine the direction of activities
- Motion: To form Standardization of live Gas Flow Rate Study Group
- **By** / 2nd: Shuji Moriya (Tokyo Electron Yamanashi) / Seiji Ishihara, (Flow Techno Service)
- Discussion: None

Vote: 11 in favor and 0 opposed. Motion passed.

9 Action Item Review

9.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

10 Next Meeting and Adjournment

The next meeting of the Japan Gases & Facilities Committee is scheduled for Friday, September 27, 2013, 15:00-17:00, at SEMI Japan, Tokyo, Japan.

Prior to the Committee meeting, 5 year-review TF and SG will be held on the same day.





Respectfully submitted by: Naoko Tejima Manager, Standards SEMI Japan Phone: +81.3.3222.5804 Email: ntejima@semi.org

Minutes approved by:

Hiromichi Enami (Hitachi High Technologies), Co-chairs	July 25, 2013
Isao Suzuki (MKS Japan), Co-chairs	July 24, 2013

Table 8 Index of Available Attachments #1

#	Title	
1	JA_G+F_Previous_Mtg_Minutes_130628	
2	SEMI_Staff_Report_13628	
3	NA_Facilities_and_Gases_Comm_Report_130628	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.